

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of
Stefan BADER et al.

Serial No.: 10/696,882

Filed: October 30, 2003

For: Method for Depositing a Material on a Substrate
Wafer

Examiner: RAO, G. Nagesh
Group Art: 1722

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

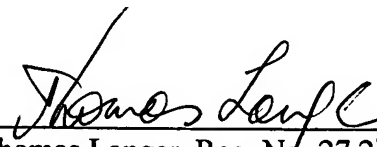
SIR:

An IDS was filed on October 30, 2006. Applicants respectfully request that the Examiner consider this previously submitted IDS.

Enclosed is an English translation of the German Examination Report dated August 10, 2006 and issued in the corresponding German Application No. 102 50 915.8-43 cited in the IDS filed on October 30, 2006. This German Examination report discusses the prior art listed in the IDS filed October 30, 2006.

Respectfully submitted,
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By


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Dated: December 26, 2006

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)		Application Number	10/696,882
		Filing Date	October 30, 2003
		First Named Inventor	Stefan BADER
		Art Unit	1722
		Examiner Name	RAO, G. Nagesh
Sheet 1 of 1	Attorney Docket Number	5367-47RCE	

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
		German Examination Report dated August 10, 2006 issued for the corresponding German Application No. 102 50 915.8-43	

Examiner Signature	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

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